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Atty. Docket # 99-CT-371/DP2

**Serial No. 10/693,639**

## List of Documents

**Cited by Applicant**  
(Use several sheets if necessary)

Applicant: Michele VULPIO

**Filing Date: October 24, 2003**

Group: 1734

## U.S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

[illegible]

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

SM	AA4	Raupp, G. B. et al. "Conformality of SiO <sub>2</sub> films from tetraethoxysilane-sourced remote microwave plasma-enhanced chemical vapor deposition", Journal of Vacuum Science and Technology (Vacuum, Surfaces and Films), May-June 1995 pp. 676-680, XP002143946.
EN	AA5	European Search Report for European Patent Application No. 00830153.3. dated July 31, 2001.

**Examiner:**

**Date Considered:**

**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.